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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/388,826
Filing Date September 1, 1999
Inventor Weimin (Michael) Li et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner E. Kielin
Attorney's Docket No. MI22-1208
Title: Low k Interlevel Dielectric Layer Fabrication Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

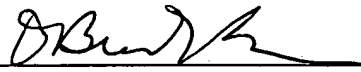
References –See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

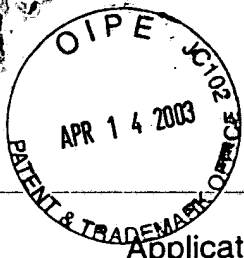
Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: 4-14-03

By: 
D. Brent Kenady
Reg. No. 40,045

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EV182661147

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Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: Nov. 7, 2002

By: _____

Frederick M. Fliegel, Ph.D.
Reg. No. 36,138

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